



Jeffrey Drue David  
"Platen And Head Rotation Rates For Monitoring Chemical Mechanical Polishing"  
10/643,583

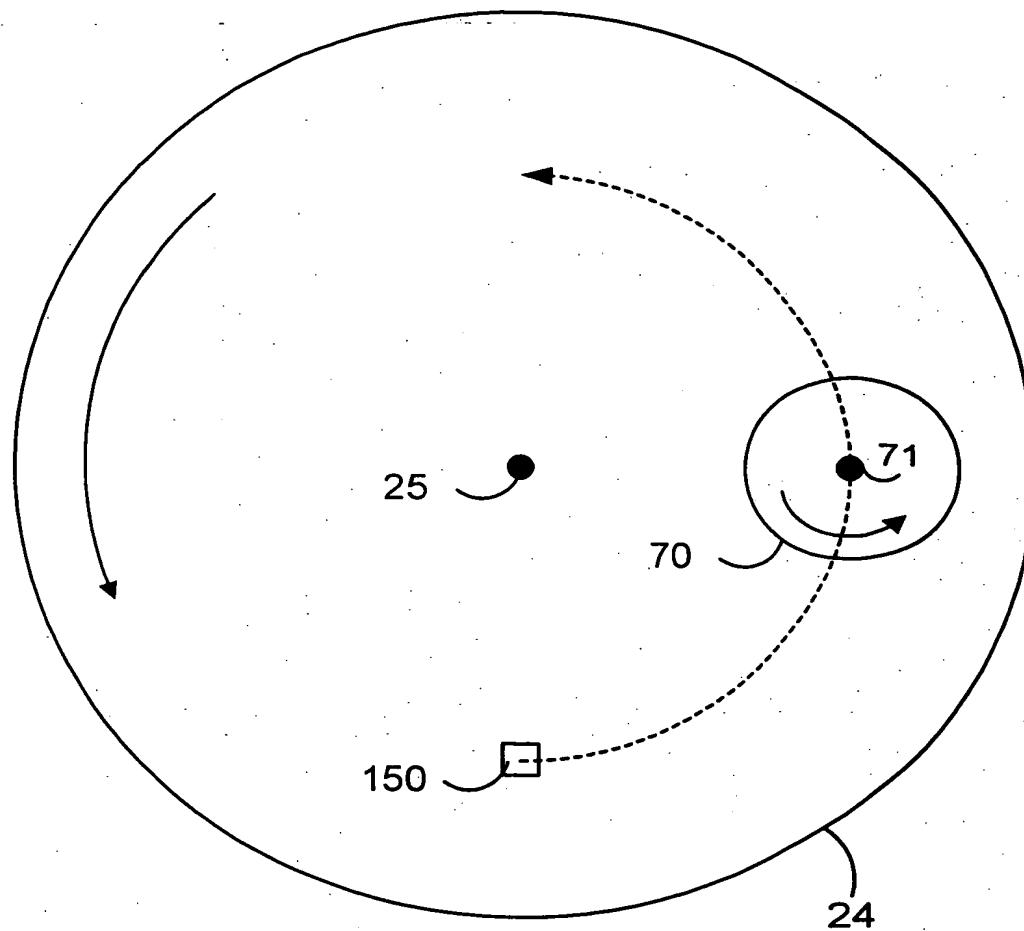


FIG. 1B



FIG. 2A

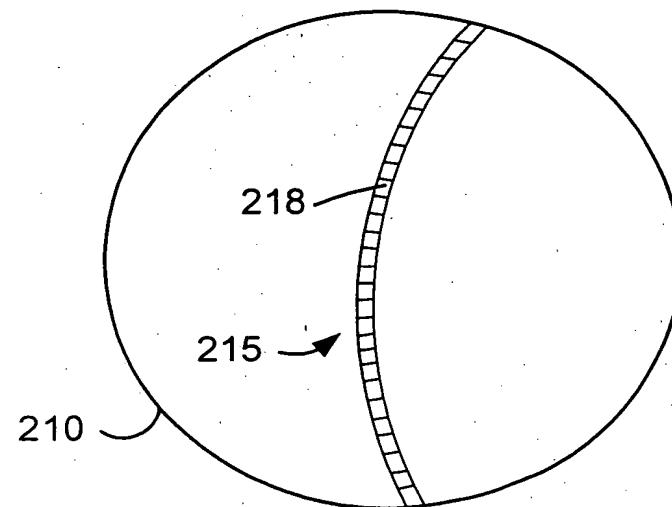
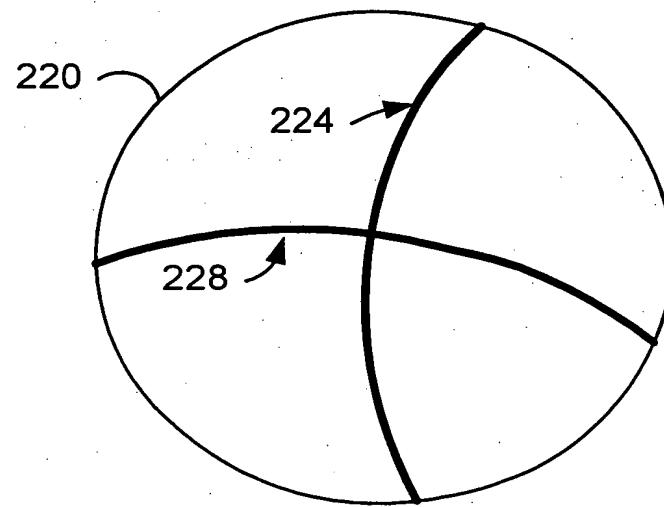


FIG. 2B



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FIG. 2C

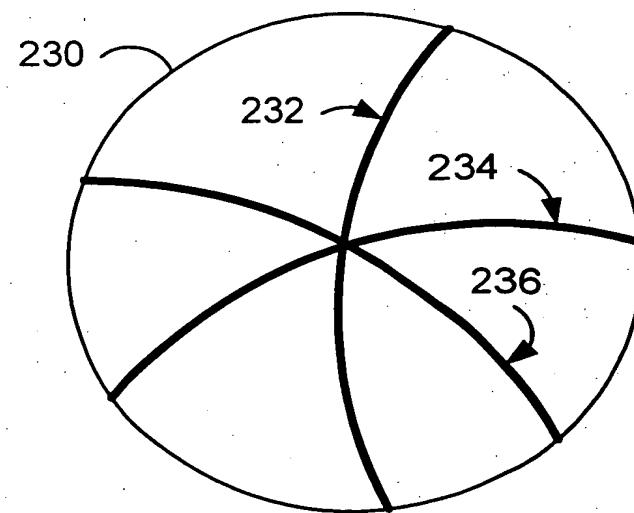
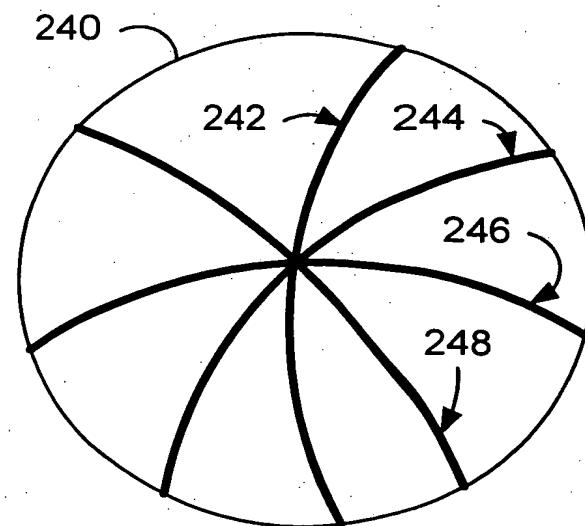


FIG. 2D



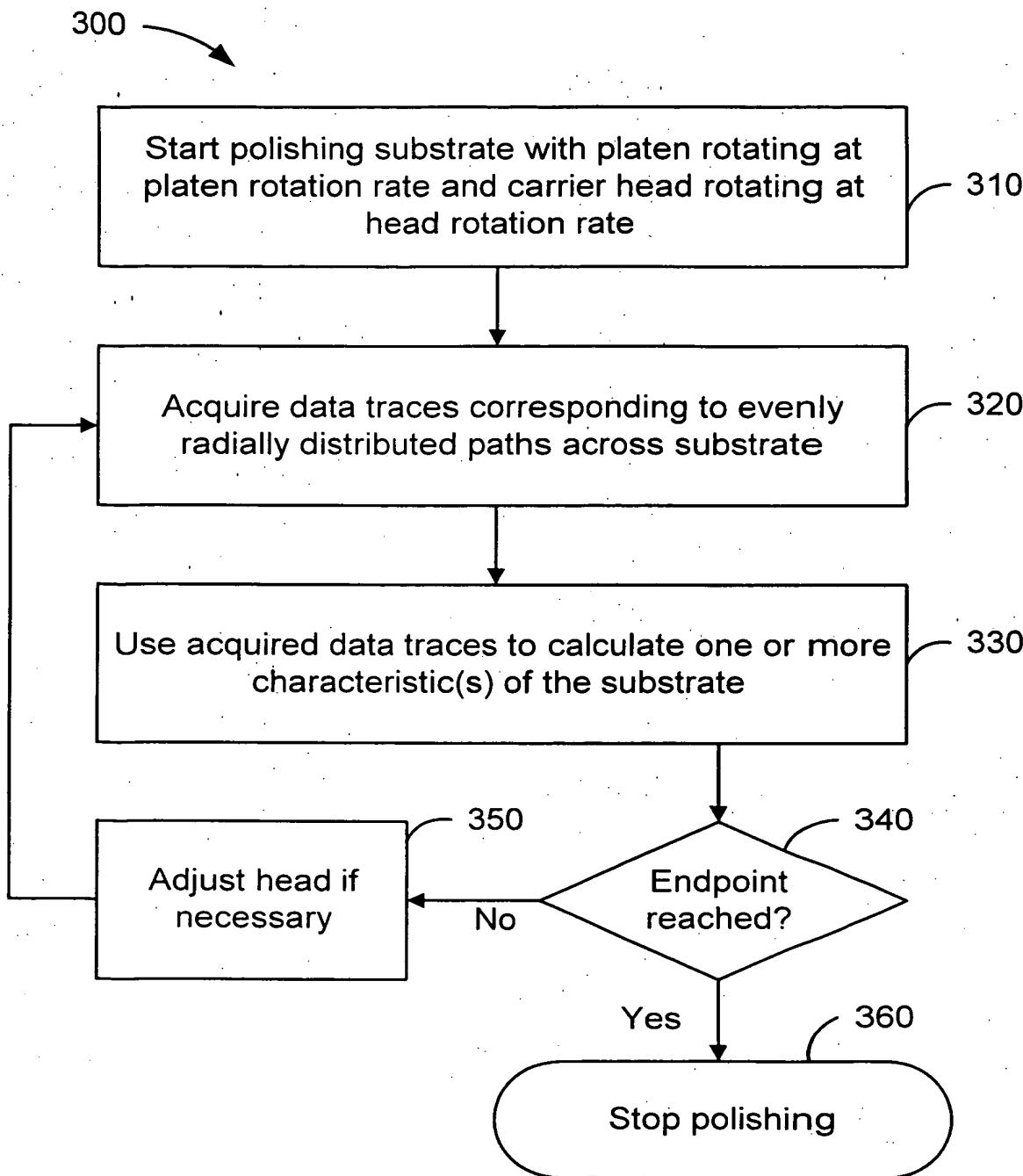


FIG. 3